

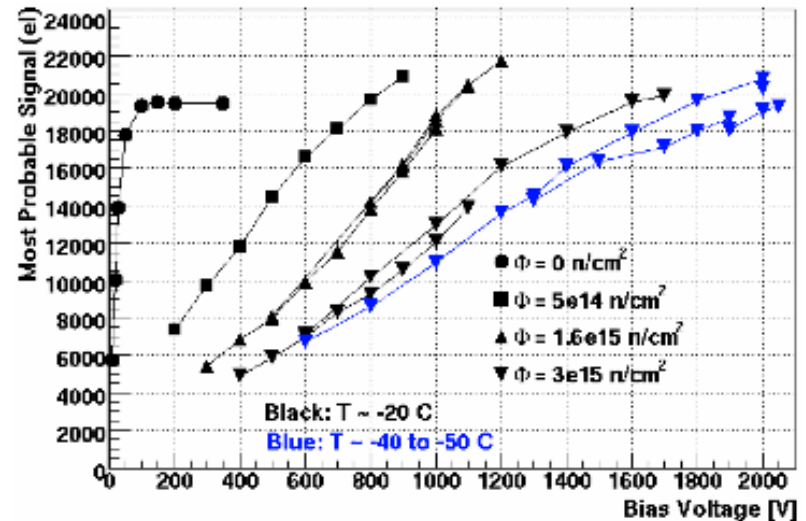


# A Charge Collection Study with Dedicated RD50 Charge Multiplication Sensors

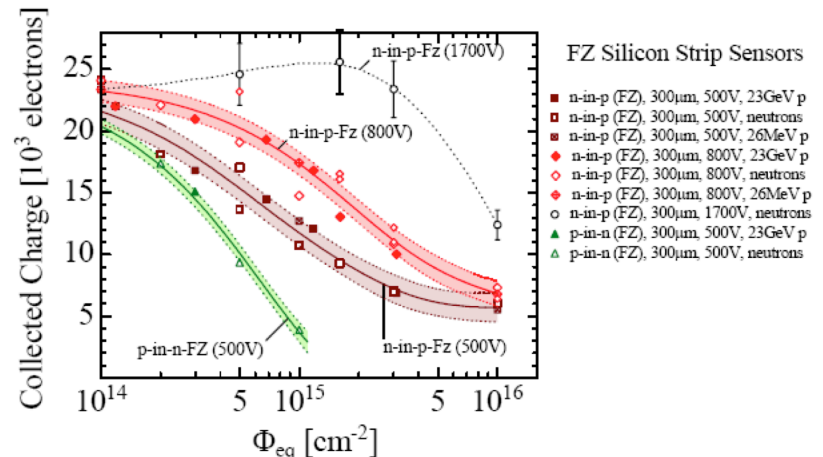
C. Betancourt, T. Barber, M. Hauser, K. Jakobs, S. Kuehn, U. Parzefall, S. Wonsak  
Albert-Ludwigs Universität Freiburg, Germany

# Charge Multiplication

- At high fluences and bias voltages, charge multiplication of the signal in the detector has been observed
- Signal is multiplied through the process of impact ionization
- Impact ionization in silicon begins when the electric field reaches 10-15 V/ $\mu\text{m}$
- Charge multiplication can be beneficial for sensors, leading to higher signal
- Same process that is responsible for charge multiplication also leads to increased noise and lower breakdown voltage



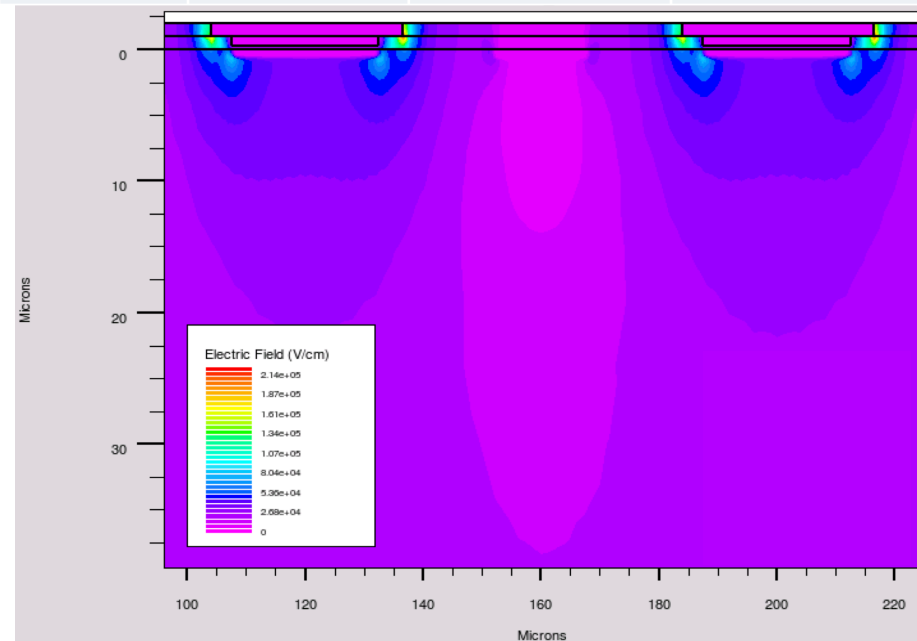
[I. Mandic, 12th RD50 workshop, 2008]



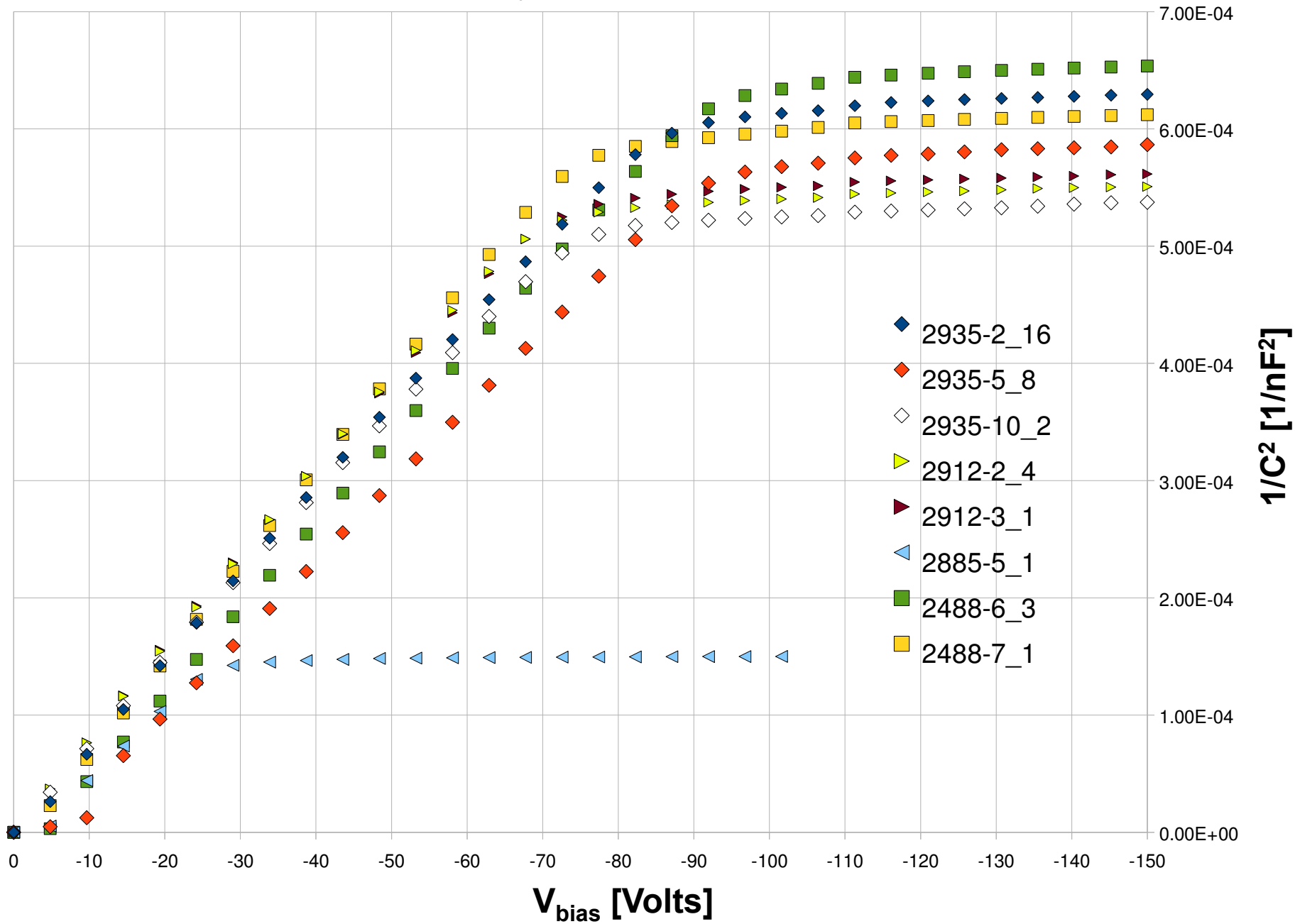
# Charge Multiplication Detectors

- 1 cm x 1 cm, n-in-p FZ strip detectors developed by MICRON
- Detectors aim to enhance the electric field near the readout strips
- Sensors of various strip width and pitch were produced, as well as sensors with floating and biased intermediate strips between readout strips
- 5 type of wafers were produced: standard, double diff. time, double implant energy, thick and thin
- IV, CV, C interstrip, and CCE measurements have been carried out

Wafer	Thickness ( $\mu\text{m}$ )	Type	Resisivity ( $\text{k}\Omega \text{ cm}$ )
2935-2 2935-5 2935-8	305 $\pm$ 15	Standard	13
2935-10	305 $\pm$ 15	Standard w/ double diffusion time	13
2912-2 2912-3	300 $\pm$ 15	Standard w/ double implant energy	10-13
2488-6 2488-7	675 $\pm$ 30	Standard thick	8
2885-5	150 $\pm$ 10	Standard thin	10

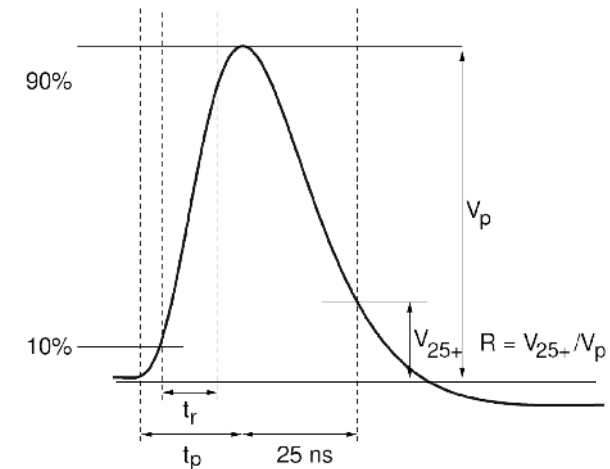
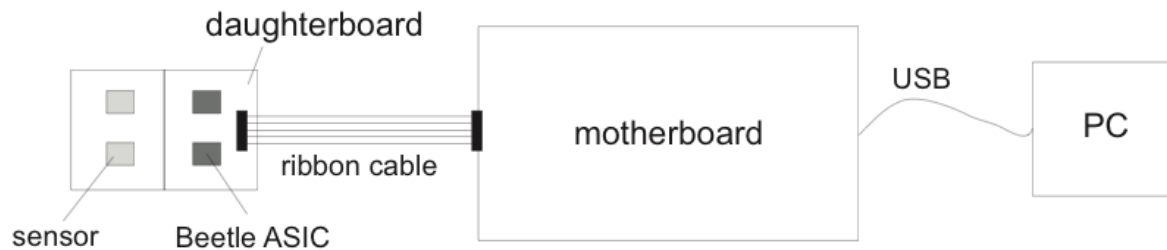
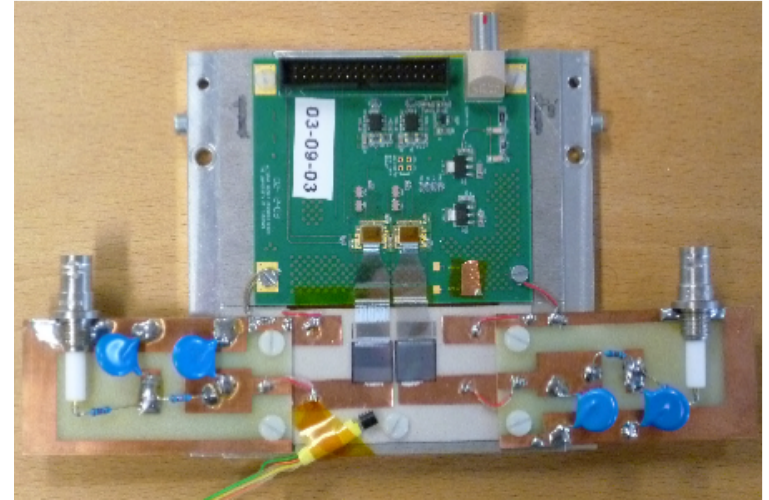


# Comparison: Sensors with different thickness



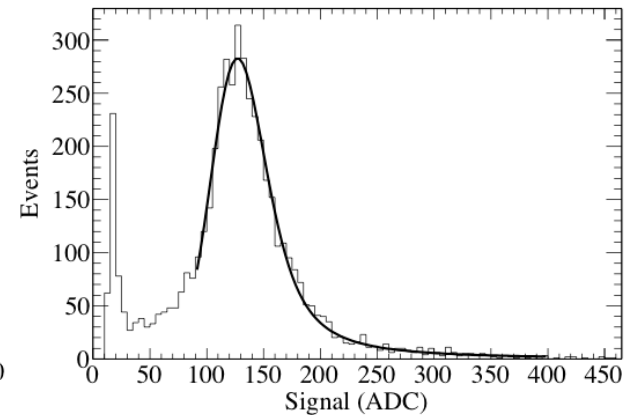
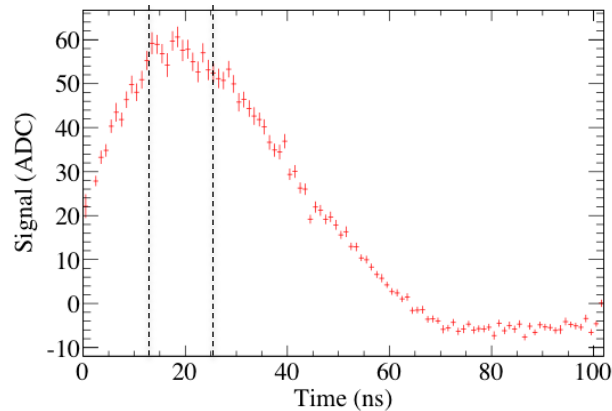
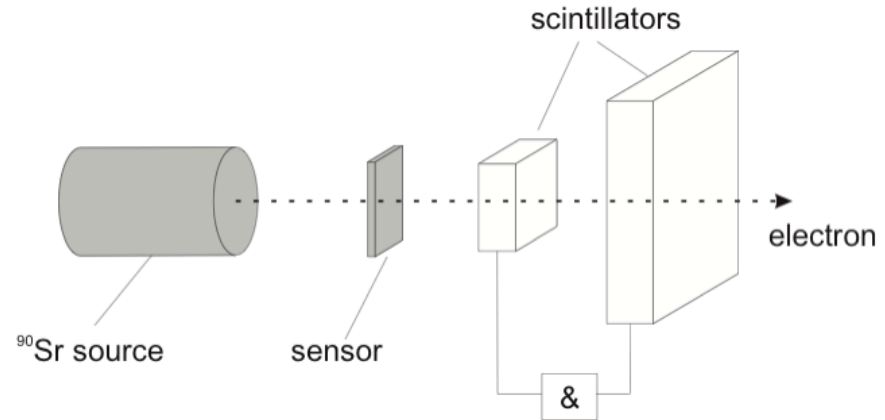
# ALIBAVA Readout System

- Charge collection measurements are done through the ALIBAVA readout system
- The daughterboard carries 2 analog front-end ASIC (Beetle) chips, which perform amplification and shaping of the signal
- The analog signal is sent to the motherboard, controlled by an FPGA, and converted into digital counts using a 10-bit ADC (Analogue to Digital Converter)
- The raw data is sent to a PC from the motherboard using a USB connection, and analyzed by custom software based off the ROOT framework



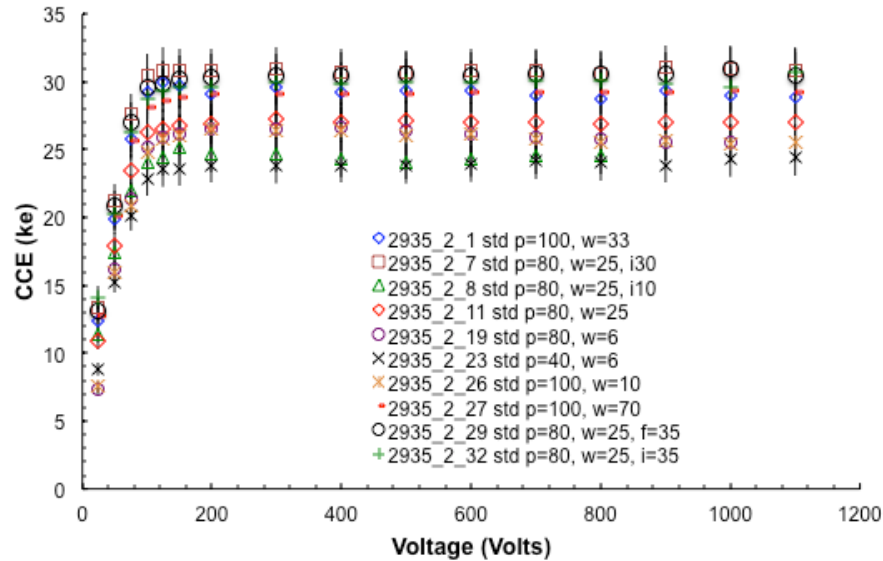
# Beta Source Measurements

- MIPs from a  $^{90}\text{Sr}$  source are used to perform charge collection measurements
- Time between trigger signal and edge of a 10 MHz clock is measured by the ALIBAVA TDC
- For each event, channel with largest SNR is chosen, and mean is calculated for each 1 ns time bin
- Only events in 10 ns window around max are considered
- Resulting spectrum is fitted with a convolution of a Gaussian and Landau distribution to determine MPV



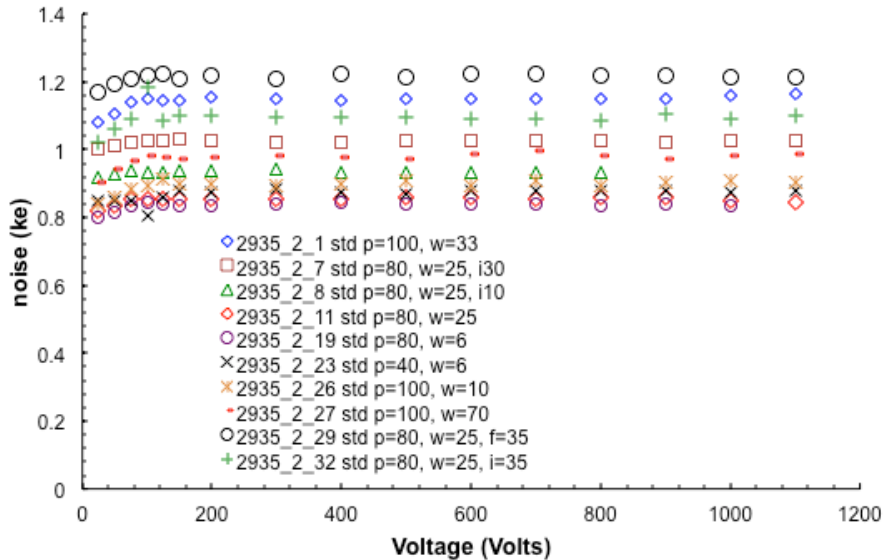
# Unirradiated Results

CCE

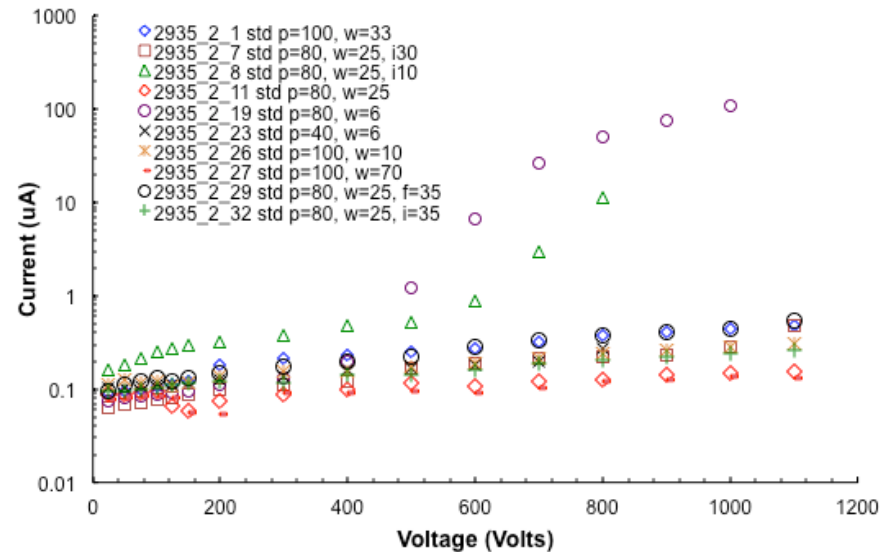


- Full depletion reached at 100-125V
- No charge multiplication observed up to 1100V on any sensor
- Large spread of collected charge for sensors from a given wafer, no clear correlation on geometry
- Most sensors show no breakdown up to 1100V

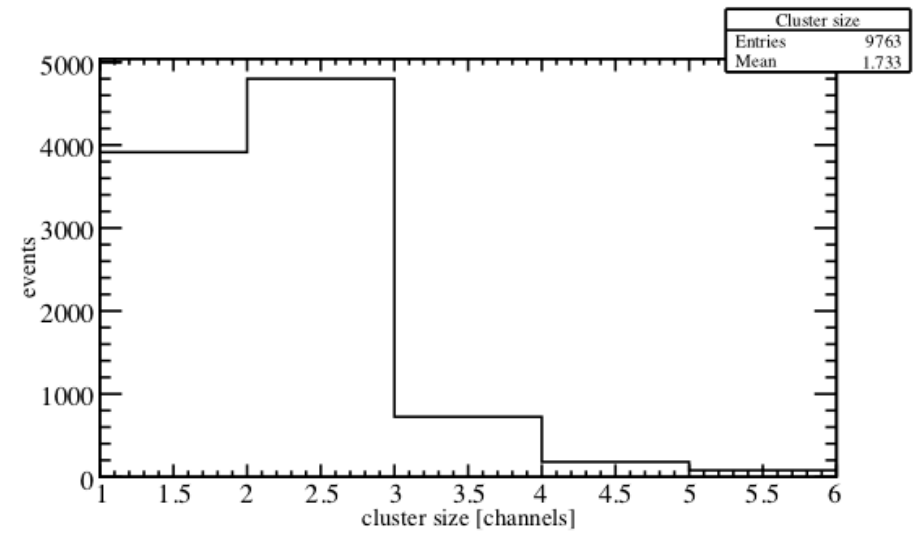
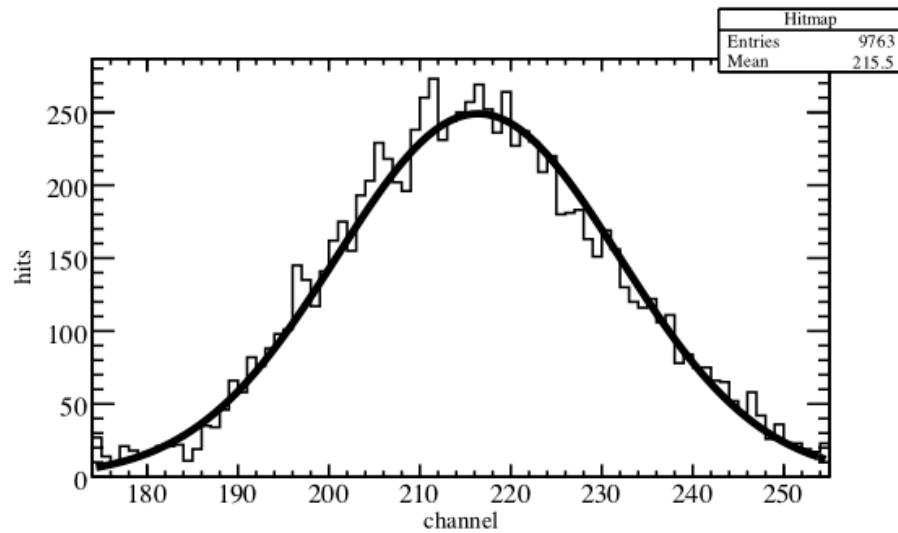
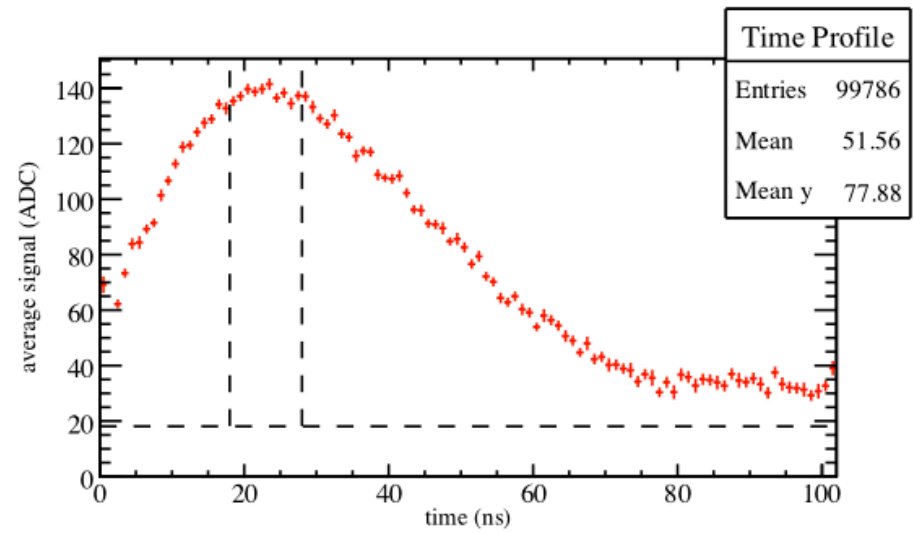
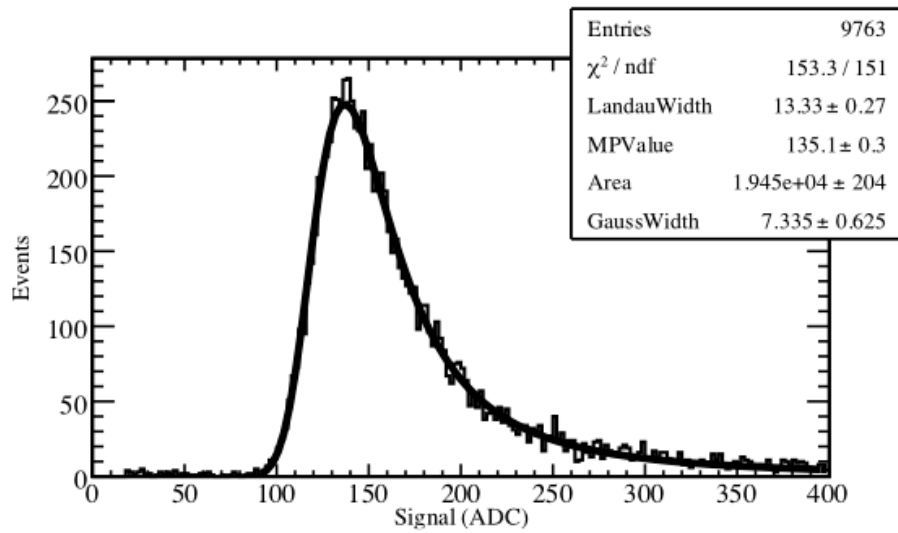
Noise



IV

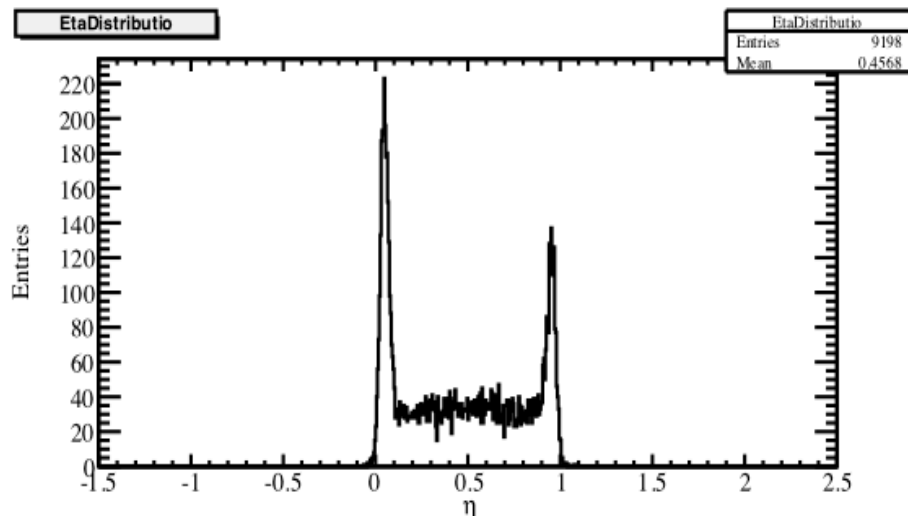
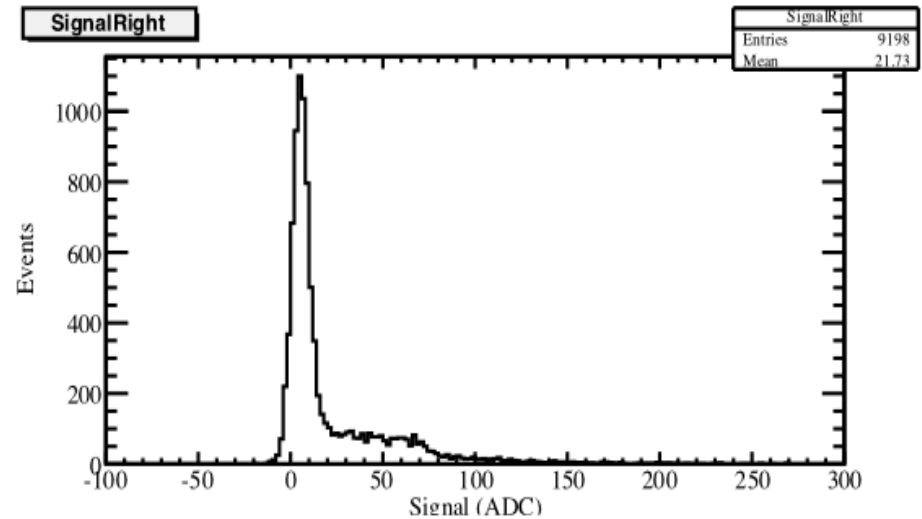
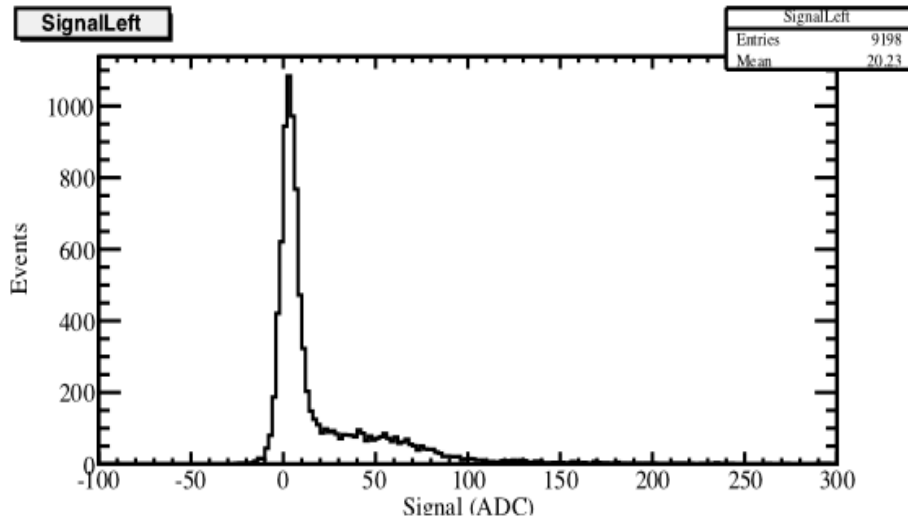


2935-2-27, 200V, CCE (ke) =  $29.14 \pm 1.61$



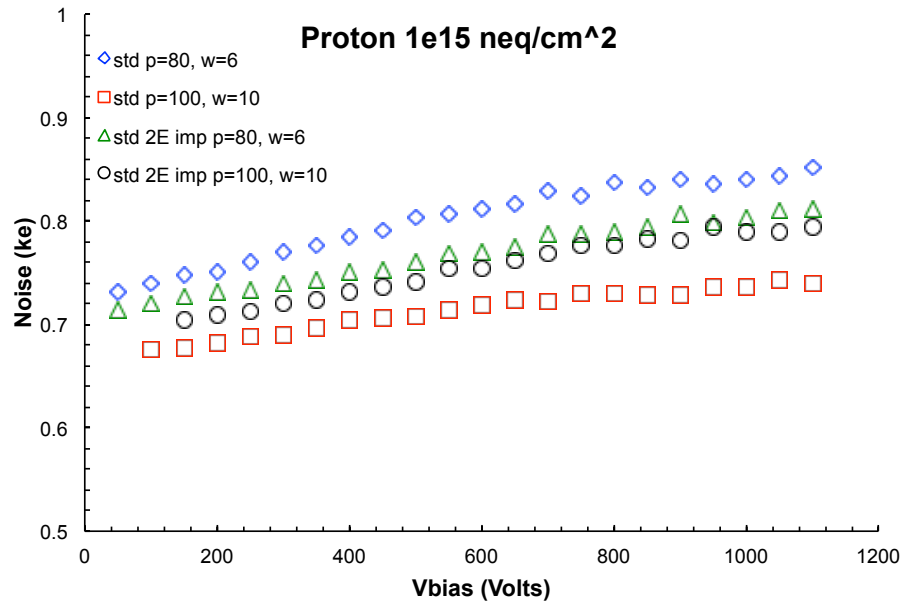
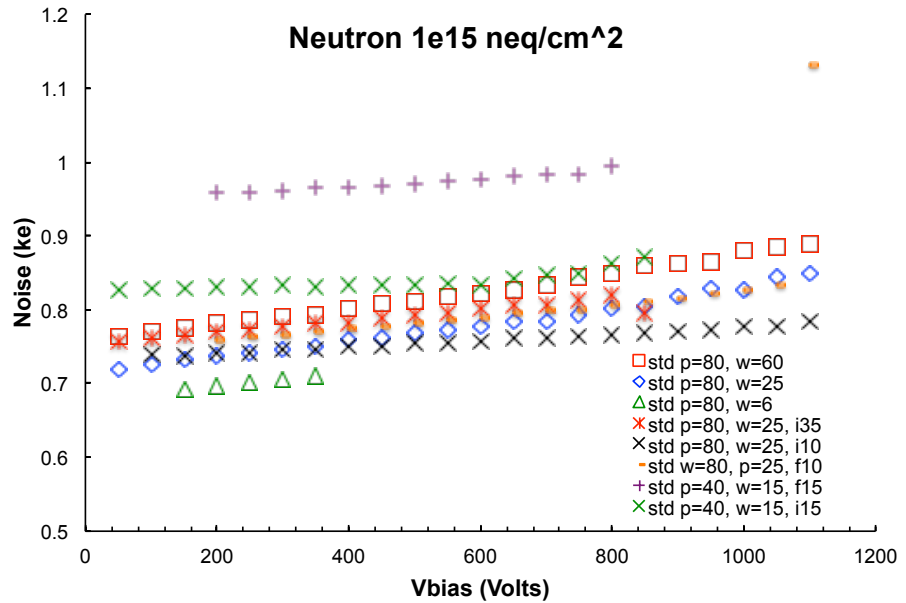
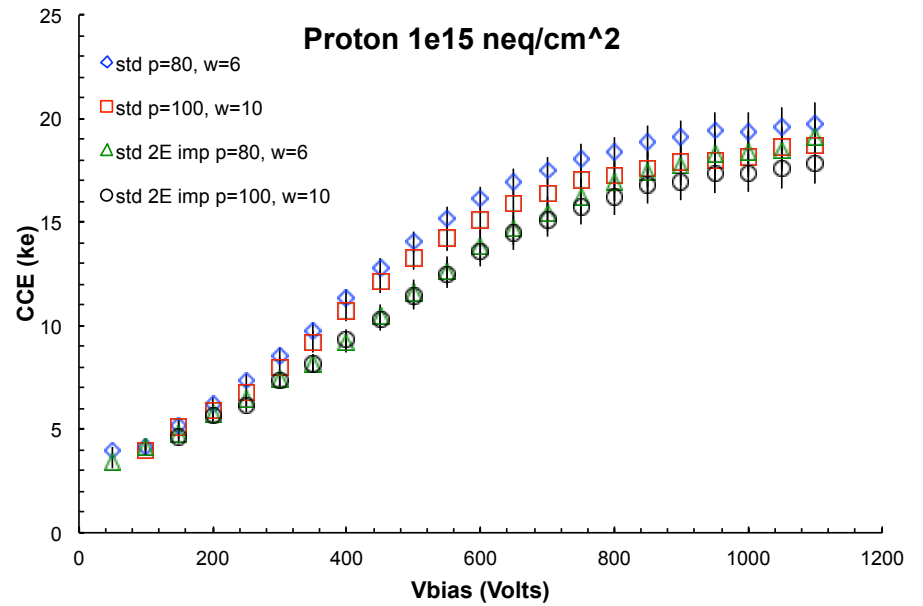
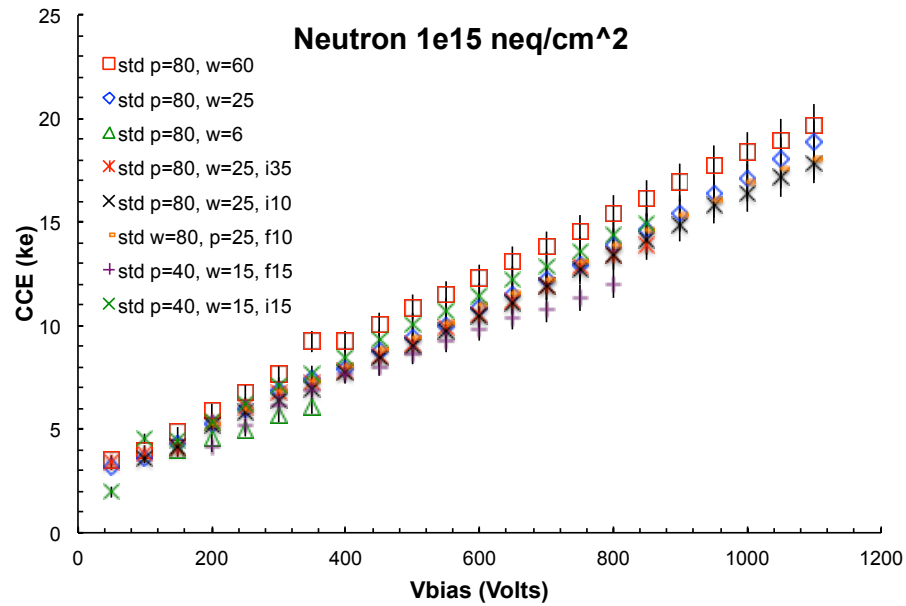


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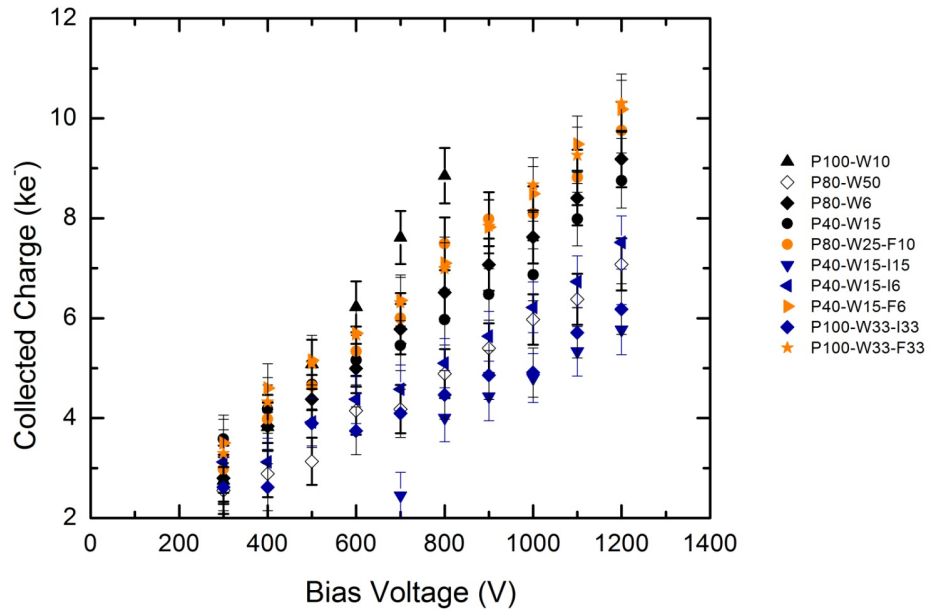
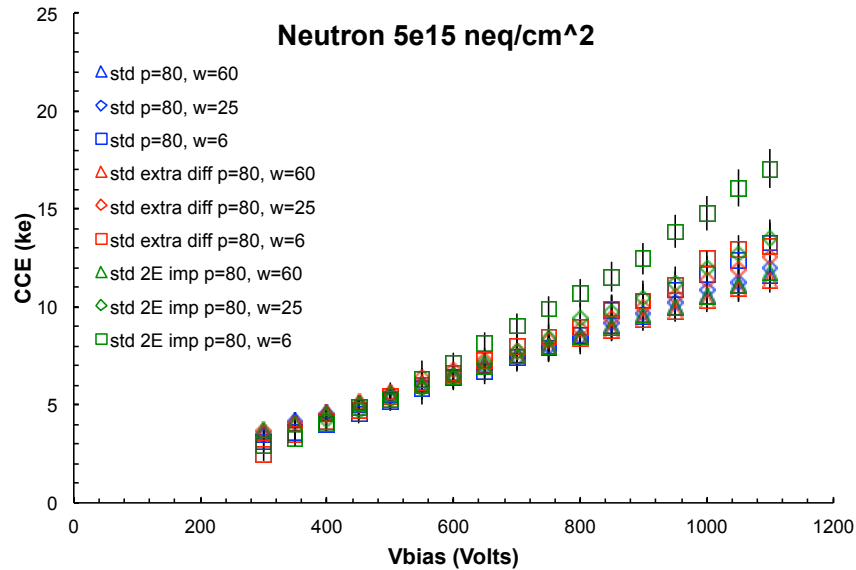


- Cluster distribution has too many 2-Hit clusters
- Sharp peaks around 0 and 1 of the  $\eta$  distribution with a flat area in-between
- Signal on neighbors not as expected (superposition of two separate distributions?)
- Asymmetry present in  $\eta$  distribution

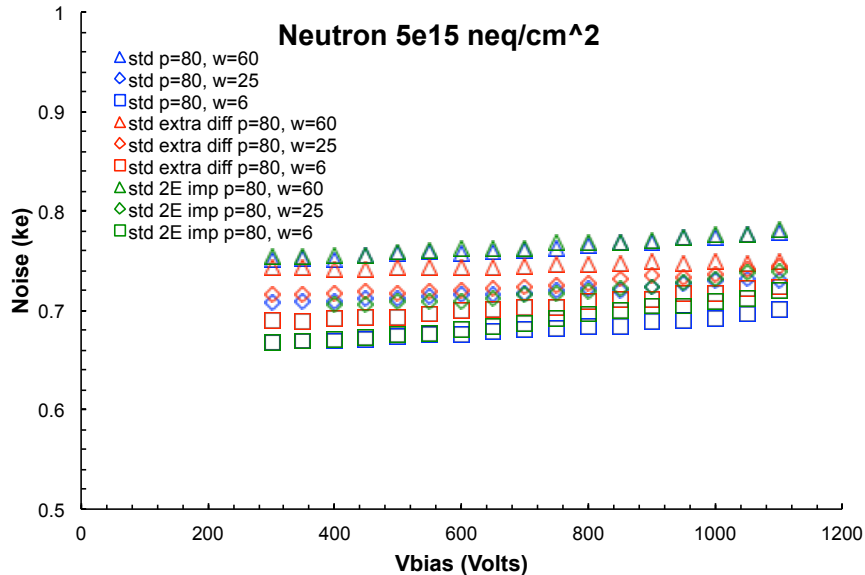
# Irradiated Detectors



# Irradiated Detectors

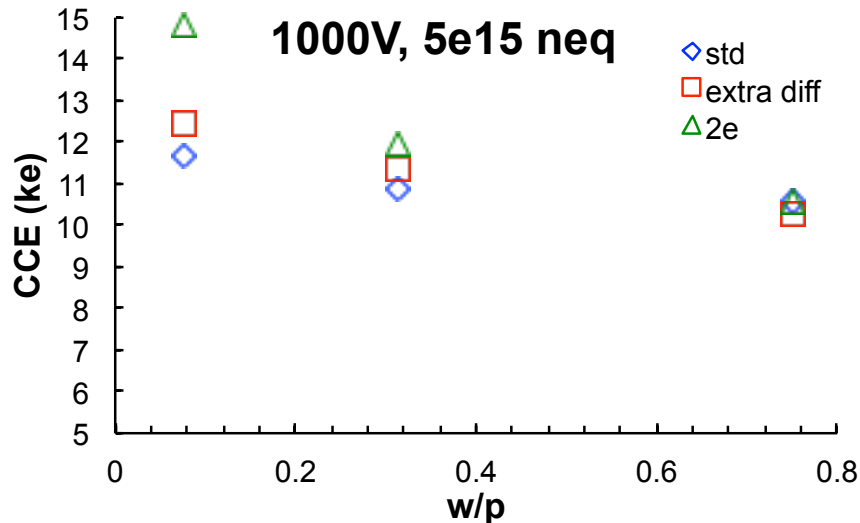
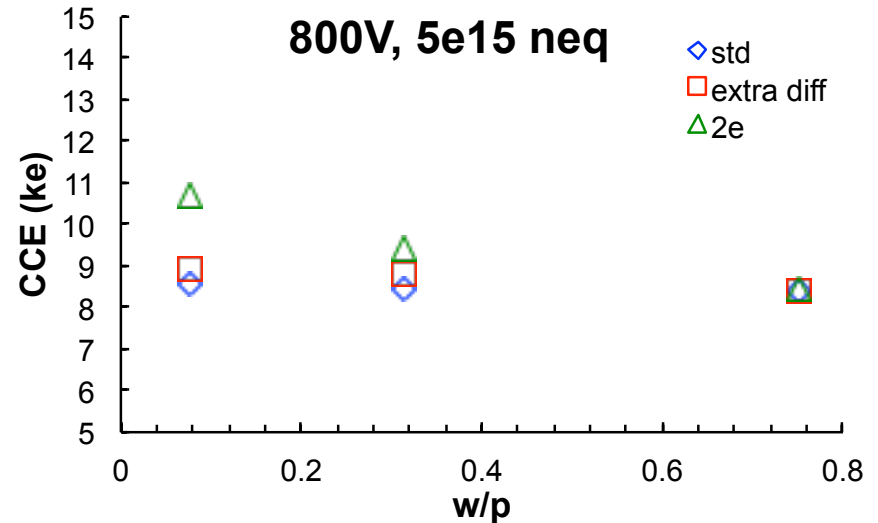
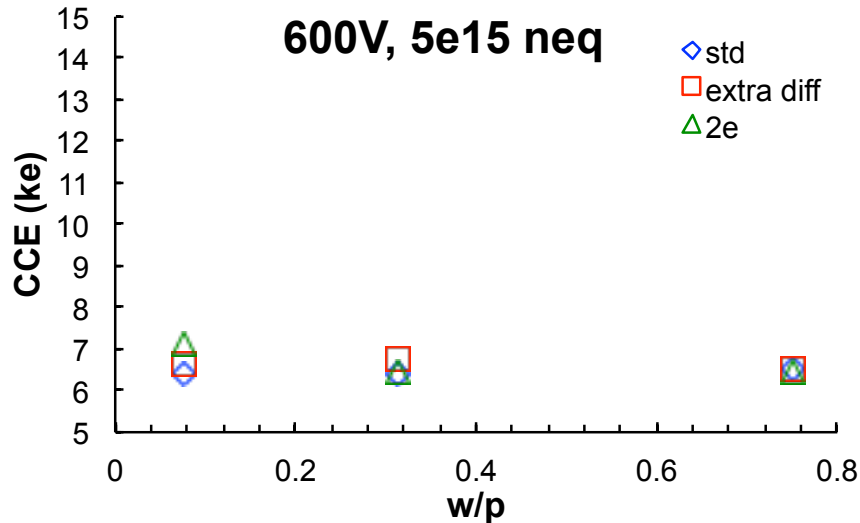


[G. Casse, 9th RESMDD, Florence 10 Oct 2012]



- One sensor (2E imp w/p=6/80) shows clear signs of CM past 600V with no significant increase in noise
- Detectors with floating intermediate strips increase charge compared to no intermediate strip detectors
- Detectors with biased intermediate strips decrease charge compared to no intermediate strip detectors

# Irradiated Detectors



- CM only seen at  $V_{\text{bias}} > 600\text{V}$
- Both Extr. Diff. and 2E imp. Show signs of CM with respect to standard wafer
- Lower w/p ratio leads to more pronounced multiplication (as expected)

# Summary

- The RD50 collaboration is investigating charge multiplication sensors as a viable option for radiation hard detectors
- This study focuses on MICRON strip detectors of various geometries
- No CM observed at  $1e15 n_{eq}/cm^2$  for both proton and neutron irradiated samples
- At  $5e15 n_{eq}/cm^2$  one sensor ( $w/p=6/80$  2E imp) shows pronounced signs of CM without a corresponding increase in the noise
- Detectors with floating intermediate strips tend to enhance charge collection while detectors with a biased intermediate strip tend to decrease charge collection
- Sensors with Double Diff. and Double Imp. Energy show enhanced charge for  $V_{bias} > 600V$  at  $5e15 n_{eq}/cm^2$ , with lower  $w/p$  leading to more charge

# Acknowledgements

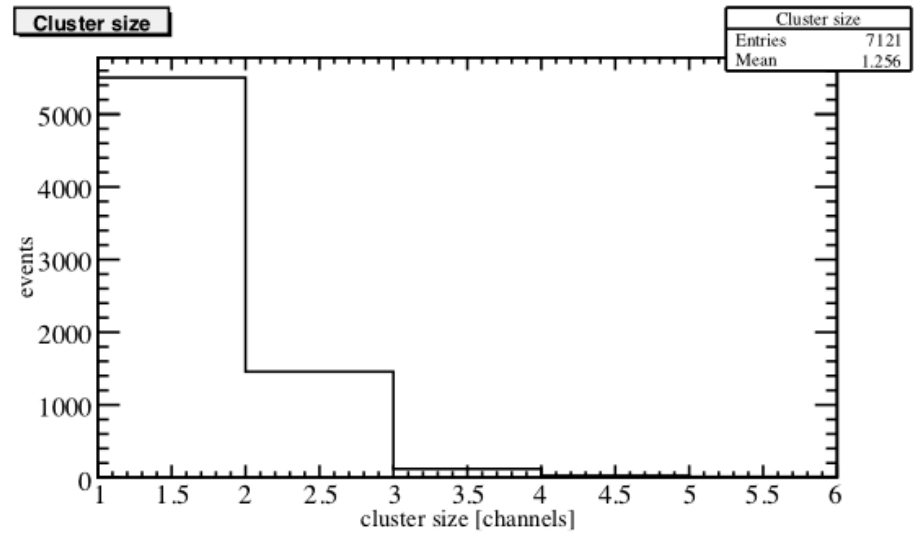
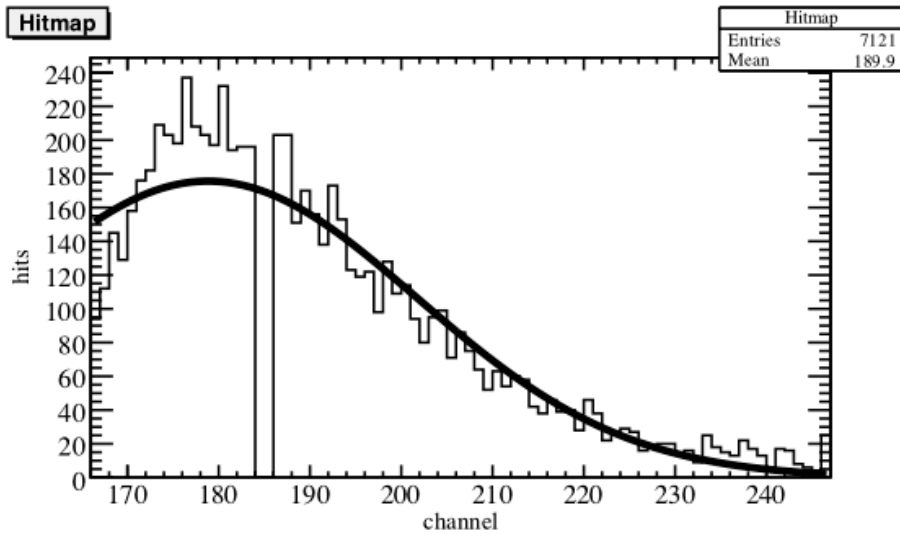
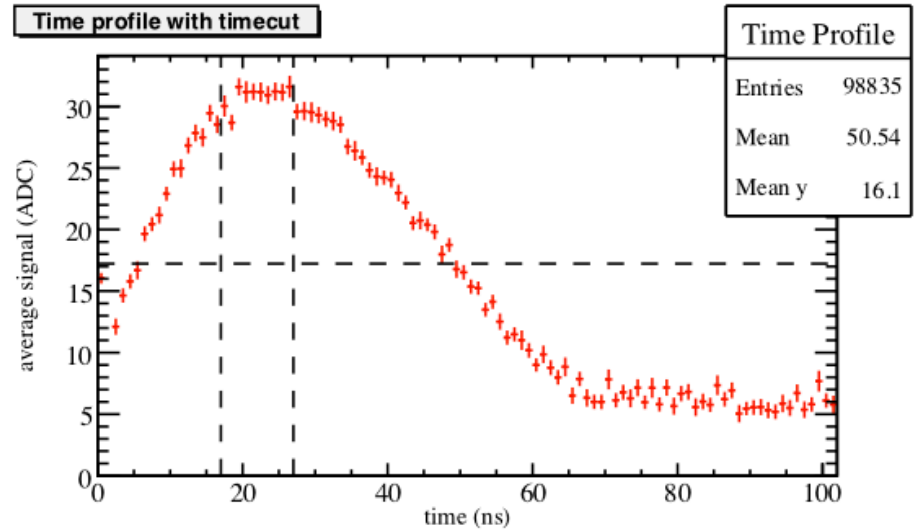
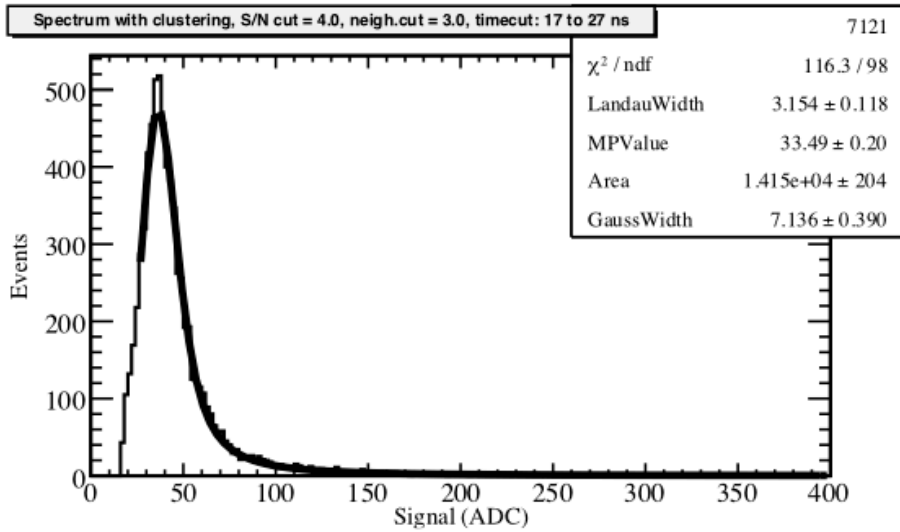
We would like to thank the irradiation teams and  
Ljubljana and Karlsruhe

Discussions with Gianluigi Casse from Liverpool

The RD50 community as a whole

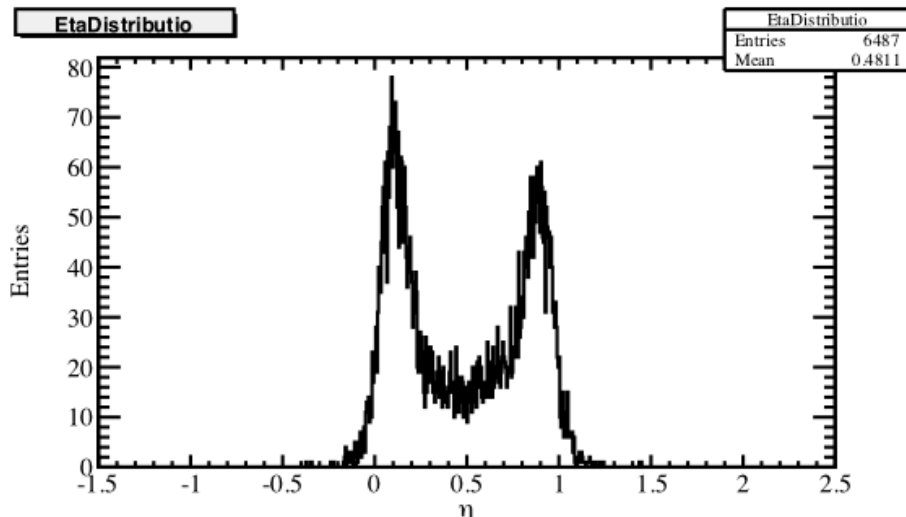
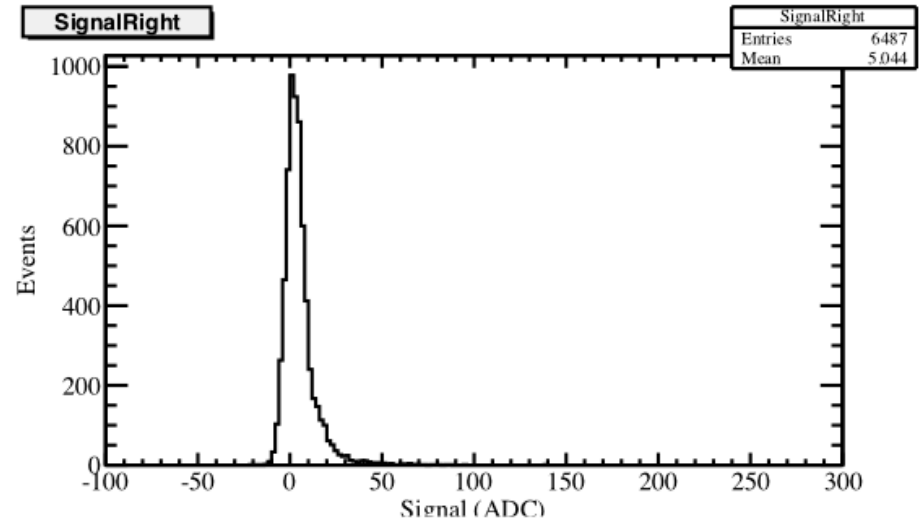
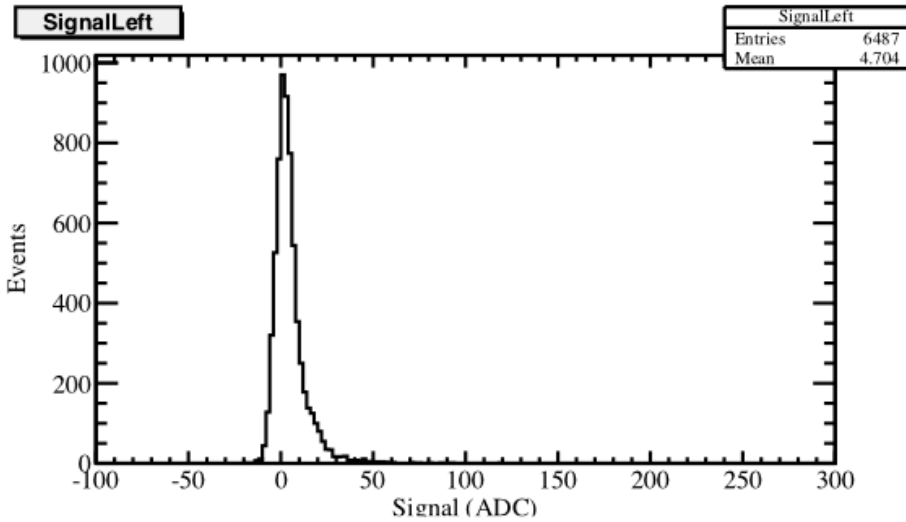
# BACKUP SLIDES

# 3D\_S2, 20V



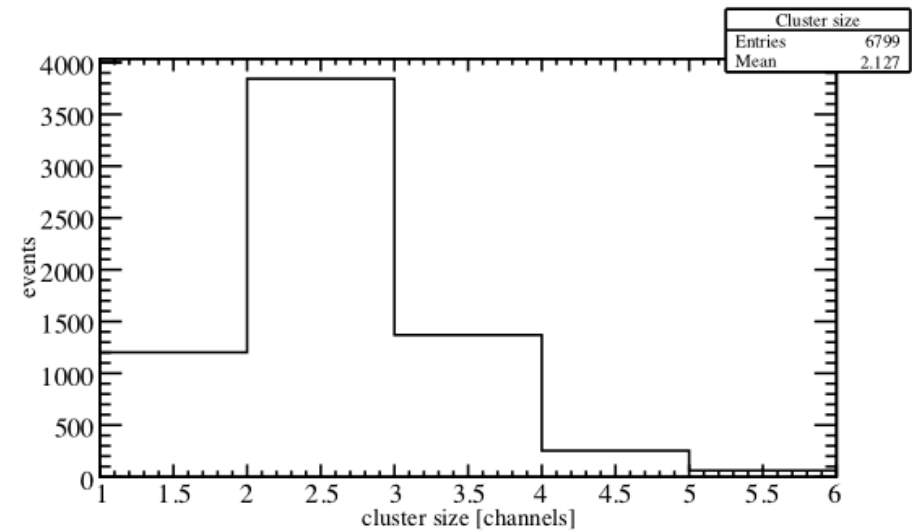
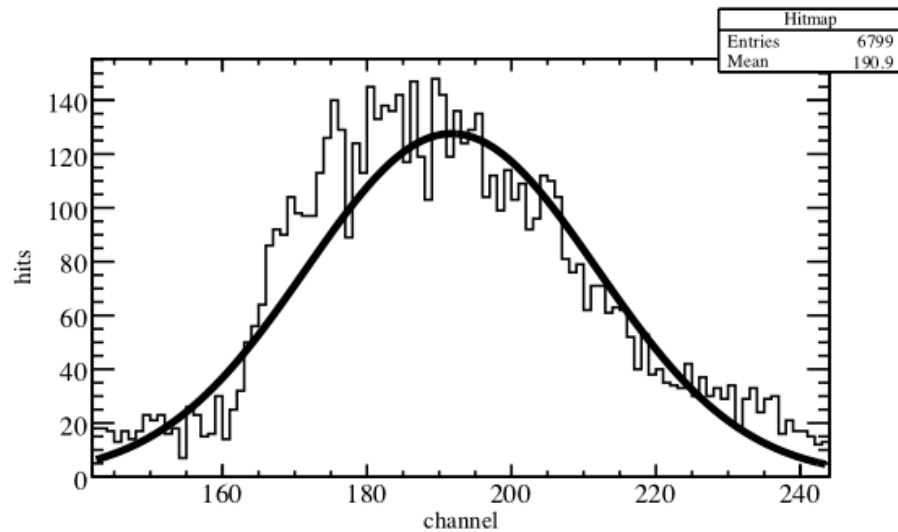
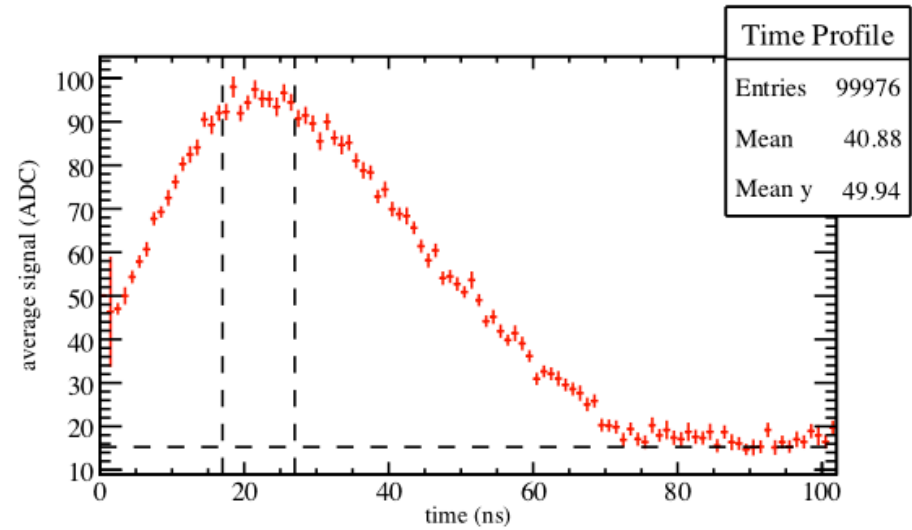
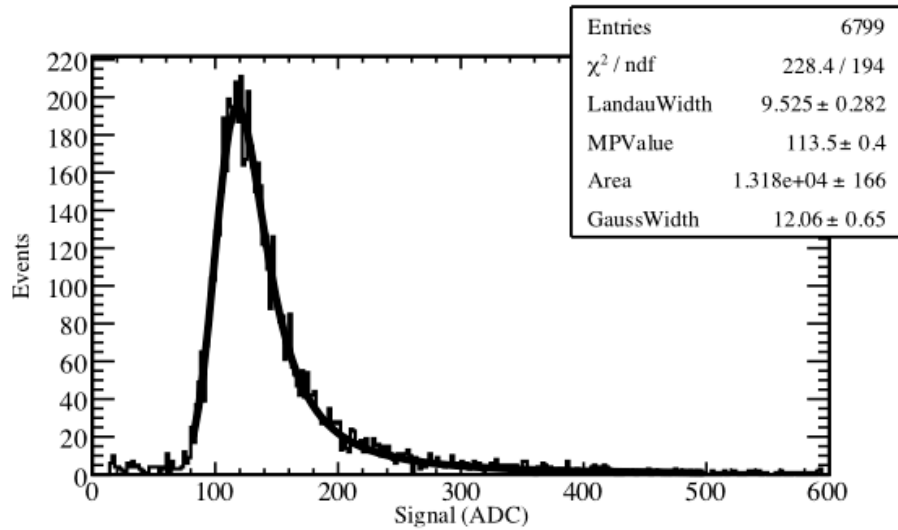


# 3D\_S2, 20V

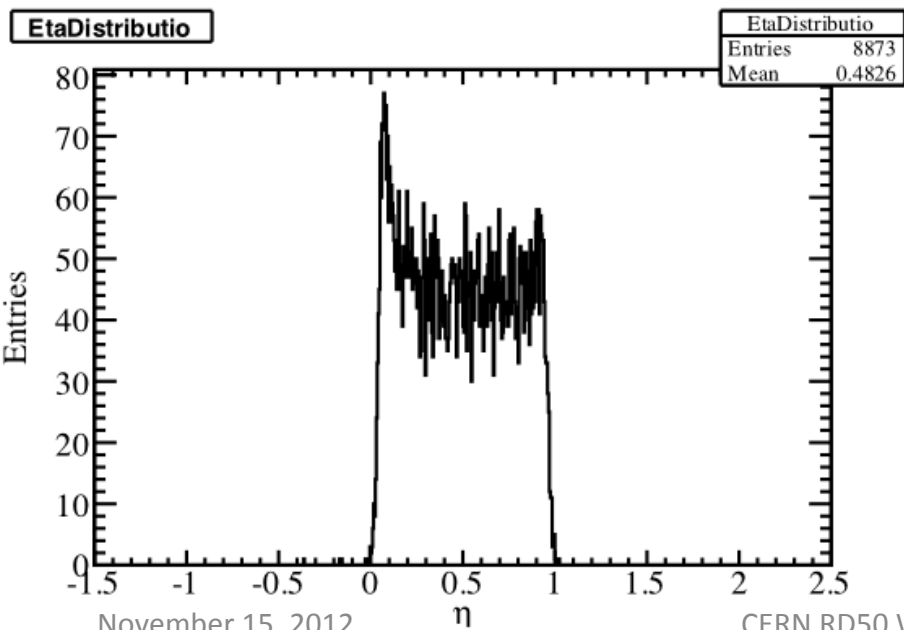
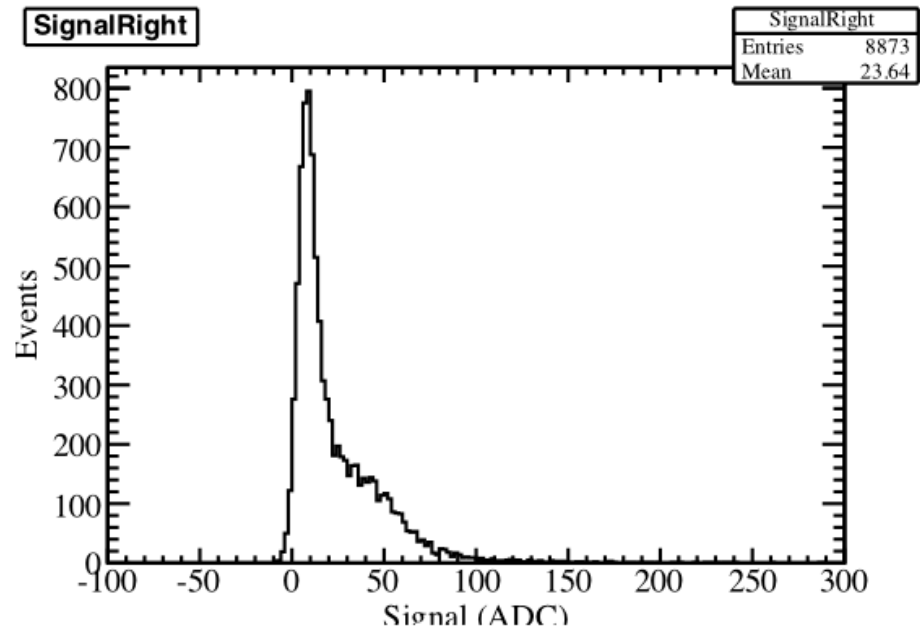
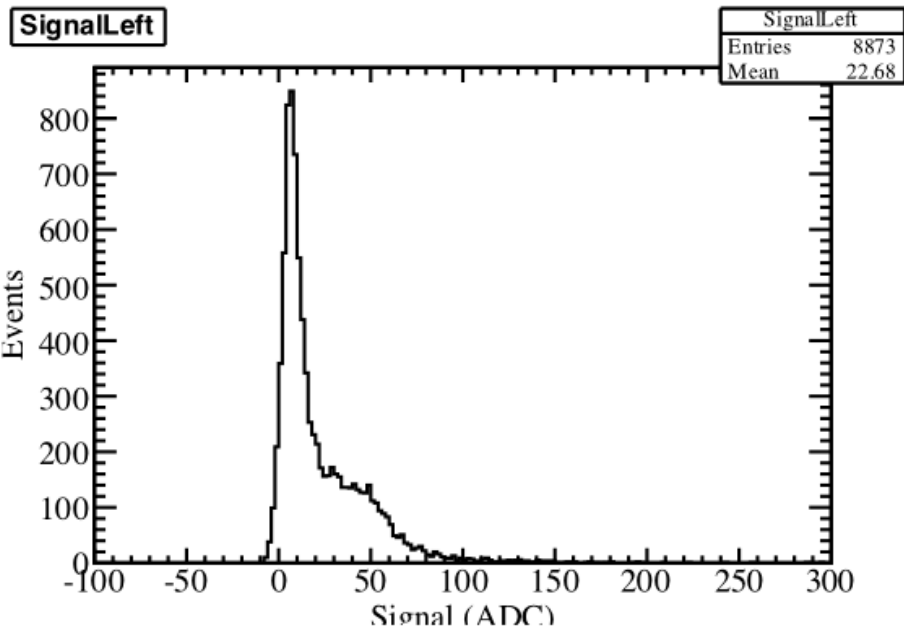


- Cluster distribution looks as expected
- Small asymmetry evident in the  $\eta$  distribution (possibly from the way the ASIC reads charge out from left to right, issues with the ALIBAVA firmware, or some other unknown cause)

# W53-BZ4A-P4, 200V, CCE (ke) = $24.19 \pm 1.33$



# W53-BZ4A-P4, 200V, CCE (ke) = $24.19 \pm 1.33$



- Cluster distribution dominated by 2-Hit and 3-Hit clusters
- $\eta$  distribution makes no sense!
- Hidden distribution more evident on neighbor's signals
- This detector used to calibrate our daughter boards (part of the reason we see too high of a signal on some MICRON sensors?)